

IN THE CLAIMS:

Please enter the current claim set as follows:

1. (Previously presented) An apparatus for use with a three-dimensional object having a feature and an optical scanner having a scanning surface, the apparatus comprising:
a mounting structure adapted to be disposed on the scanner, said mounting structure having a pitch calibration mark adapted for being read by the scanner, said mounting structure further being adapted to position the object so that the object is adjacent to the scanning surface of the scanner and at a first pre-determined distance from the calibration mark.
2. (Original) The apparatus of claim 1 wherein the mounting structure is adapted to removably abut the optical scanner.
3. (Original) The apparatus of claim 2 wherein the mounting structure comprises an alignment surface adapted to abut the object, the alignment surface being disposed at a second pre-determined distance from the calibration mark.
4. (Original) The apparatus of claim 3 wherein the alignment surface is adapted to abut the object at a point spaced apart from the scanning surface.
5. (Original) The apparatus of claim 4 wherein the alignment surface is one of generally cylindrical and generally spherical in shape.
6. (Original) The apparatus of claim 5 wherein the mounting structure further comprises:
a first frame member having a bottom surface and a top surface, the bottom surface adapted for placement on the scanning surface of the scanner, and the top surface adapted for receiving the object; and

a second frame member having a proximate end and a distal end, the proximate end being joined with the first frame member and the alignment surface being disposed on the distal end.

7. (Original) The apparatus of claim 3 further comprising a computer adapted to receive data from the optical scanner.

8. (Previously presented) An apparatus for measuring a feature on a side of a wafer carrier, comprising:

an optical scanner having a scanning surface; and
a mounting structure disposed on said scanner and configured to position said wafer carrier over said scanner surface, said structure having a first pitch calibration mark adapted to be read by the scanner and having an alignment surface adapted for engagement with the wafer carrier.

9. (Original) The apparatus of claim 8 wherein the mounting structure is adapted to removably abut the optical scanner.

10. (Original) The apparatus of claim 8 wherein the wafer carrier side has an alignment pin having a length and wherein the mounting structure is further adapted to position the wafer carrier so that the carrier side is in a generally parallel, spaced-apart relationship with the scanning surface of the scanner by a distance that is greater than the length of the alignment pin.

11. (Previously presented) The apparatus of claim 8 wherein the optical scanner has a scan head adapted to move in a scanning direction, the apparatus further comprising:

a second pitch calibration mark located on the mounting structure and adapted for being read by the scanner, the second calibration mark located at a first pre-determined distance from the first calibration mark, the second calibration mark and the first

calibration mark defining a line running generally parallel to the scanning direction.

12. (Previously presented) The apparatus of claim 8 wherein the optical scanner has a scan head adapted to move in a scanning direction, the apparatus further comprising:

a second pitch calibration mark located on the mounting structure and adapted for being read by the scanner, the second calibration mark located at a first pre-determined distance from the first calibration mark, the second calibration mark and the first calibration mark defining a line running generally orthogonal to the scanning direction.

13. (Previously presented) The apparatus of claim 11 further comprising:

a third pitch calibration mark and a fourth pitch calibration mark, said third and fourth calibration marks located on the mounting structure and adapted for being read by the scanner, the third and fourth calibration marks located at a second pre-determined distance from one another and defining a line running generally orthogonal to the scanning direction.

14. (Original) The apparatus of claim 13 wherein the alignment surface is adapted to abut the wafer carrier, the alignment surface being disposed at a third pre-determined distance from one of the first, second, third and fourth calibration marks.

15. (Original) The apparatus of claim 8 wherein the alignment surface is adapted to abut the wafer carrier at a point spaced apart from the scanning surface, the alignment surface being disposed at a first pre-determined distance from the first calibration mark.

16. (Original) The apparatus of claim 15 wherein the alignment surface is one of generally cylindrical and generally spherical in shape.

17. (Original) The apparatus of claim 8 further comprising a computer adapted to receive data from the optical scanner.

18. (Previously presented) An apparatus for measuring a feature on a side of a wafer carrier comprising:

a mounting structure having an alignment surface adapted for engagement with said carrier, said structure further having a first optical pitch calibration mark.

19. (Previously presented) The apparatus of claim 18 having a second optical pitch calibration mark positioned a first pre-determined distance along a first direction from said first calibration mark.

20. (Previously presented) The apparatus of claim 19 wherein said structure has a third optical pitch calibration mark and a fourth optical pitch calibration mark positioned at a second pre-determined distance from said third optical calibration mark in a second direction generally orthogonal to the first direction.

21. (Currently amended) An apparatus for measuring a feature on a side of a wafer carrier comprising:

an optical scanner having a transparent scanning surface;

a first frame member having a bottom surface and a top surface, the bottom surface being adapted for placement on the scanning surface of the scanner, and the top surface being adapted for receiving the wafer carrier side;

a second frame member having a proximate end and a distal end, the proximate end being joined with the first frame member;

a generally cylindrically-shaped alignment surface disposed at the distal end of the second frame member and adapted to abut the wafer carrier;

a brace member secured to the first and the second frame members; and

a first calibration mark on the bottom surface of the first frame member and adapted to being read by the scanner, the first calibration mark positioned at a first pre-determined distance from the alignment surface.

22. (Original) The apparatus of claim 21 further comprising a second calibration mark on the bottom surface of the first frame member and adapted to being read by the scanner, the second calibration mark positioned at a second pre-determined distance from the first calibration mark.

23. (Original) The apparatus of claim 21 wherein the alignment surface is adapted to abut the wafer carrier at a point spaced apart from the scanning surface.

24. (Cancelled)

25. (Currently amended) A method of measuring a feature of a wafer carrier comprising:

operating an optical ~~flatbed~~ scanner to obtain an image comprising:

a first image portion representing a first location point on the wafer carrier; and

a second image portion representing a second location point; and

calculating a first value from the image, the first value representing the distance between the first location point and the second location point;

wherein the image further comprises a third image portion representing a third location point and a fourth image portion representing a fourth location point, and wherein the third and fourth location points represent positions on other than the wafer carrier, the method further comprising:

calculating a second value from the image, the second value representing the

distance between the third and fourth location points; and

calibrating the optical scanner with the second value.

26. (Cancelled)

27. (Currently amended) The method of claim 26 25 wherein the step of calibrating the optical scanner comprises measuring the pixel resolution of the scanner.

28. (Currently amended) The method of claim 26 25 wherein the step of calibrating the optical scanner comprises measuring the scan line resolution of the scanner.

29. (Original) The method of claim 25 wherein the step of calculating the first value is comprised of performing a numerical best fit of the image of the first and second location points.

30. (Previously presented) An apparatus for measuring a feature on a side of a wafer carrier comprising:

means for obtaining an image;

means for positioning the wafer carrier so that the carrier side is adjacent to the image

obtaining means; and

a pitch calibration mark on the positioning means and adapted to being read by the image obtaining means.

31. (Original) The apparatus of claim 30 further comprising means for positioning the wafer carrier at a pre-determined distance from the calibration mark.

32. (Previously presented) The apparatus of claim 31 further comprising a plurality of additional pitch calibration marks on the positioning means and adapted to being read by the image obtaining means, the additional calibration marks being at a plurality of additional pre-determined distances from one another.

33. (Currently amended) An apparatus for measuring a feature of a wafer carrier, the apparatus comprising:

means for obtaining an image comprising:

a first image portion representing a first location point on the wafer carrier; and
a second image portion representing a second location point; and

means for calculating a first value from the image, the first value representing the
distance between the first location point and the second location point;

~~wherein said image obtaining means includes a flatbed scanner wherein the image~~
further comprises a third image portion representing a third location point and a fourth image
portion representing a fourth location point, and wherein the third and fourth location points
represent positions on other than the wafer carrier, the apparatus further comprising:

means for calculating a second value from the image, the second value representing the
distance between the third and fourth location points; and

means for calibrating the image obtaining means using the second value.

34. (Original) The apparatus of claim 33 wherein the second location point represents a location on other than the wafer carrier.

35. (Cancelled)

36. (Currently amended) A method of measuring a feature of a wafer carrier, comprising:

~~receiving from a flatbed scanner data representing an image comprising:~~

a first image portion representing a first location point on the wafer carrier; and
a second image portion representing a second location point; and

calculating a value from the image, the value representing the distance between the first
location point and the second location point.

37. (Original) The method of claim 36 wherein the first location point is a base of a front opening of the wafer carrier and the second location point is a location other than on the wafer carrier.

38. (Original) The method of claim 36 wherein the first location point is a center line of a first slot end wall and the second location point is the center line of a second slot end wall.

39. (Original) The method of claim 36 wherein the first location point is an end wall of one slot tooth measured at one side of an opening of the wafer carrier and the second location point is an end wall of a corresponding opposed slot tooth measured at the other side of the wafer carrier opening, and wherein the value is a slot root.

40. (Original) The method of claim 36 wherein the first location point is a first point on a slot tooth and the second location point is a second point on the slot tooth, and wherein the wafer carrier feature is a profile of the slot tooth.

41. (Original) The method of claim 36 wherein the first location point is a first point on a slot tooth and the second location point is a second point on the slot tooth, and wherein the wafer carrier feature is a slant angle of the slot tooth.

42. (Original) The method of claim 36 wherein the first location point is a base of a front opening of the wafer carrier and the second location point is a centerline of a slot tooth end wall.

43. (Currently amended) A method of analyzing a wafer carrier comprising:
receiving from a flatbed scanner data representing an image of a feature of the wafer carrier;
calculating a first value from the image, the first value corresponding to the wafer carrier feature;

retrieving a second value, the second value being derived from other than the image;
and
comparing the first value with the second value.

44. (Previously presented) A method of analyzing at least one wafer carrier comprising:
receiving a first set of data representing a first image of a feature of a first wafer carrier;
receiving a set of data representing an image of a span between two pitch calibration marks spaced by a predetermined distance and located on a frame adjacent said carrier;
calculating a pixel pitch based on said predetermined distance and the number of pixels of said image of said span between said pitch calibration marks;
calculating a first value from the first set of data and based on the calculated pixel pitch, the first value corresponding to the first wafer carrier feature; and
storing the first value in a computer readable medium.

45. (Original) The method of claim 44 further comprising:
receiving additional data corresponding to an identification number for the first wafer carrier;
storing the additional data in the computer readable medium; and
associating the additional data with the first value.

46. (Original) The method of claim 45 wherein the additional data is derived from a bar code.

47. (Original) The method of claim 44 further comprising:
retrieving the first value from the computer readable medium; and
providing the first value for use by one of a wafer handling tool and a wafer carrier handling tool.

48. (Original) The method of claim 44 further comprising:
receiving a second set of data representing a second image of the feature of a second wafer carrier;
calculating a second value from the second set of data, the second value corresponding to the feature of the second wafer carrier; and
storing the second value in the computer readable medium.

49. (Original) The method of claim 48 further comprising:
retrieving the first and second values from the computer readable medium; and
performing statistical analysis using the first and second values.

50. (Original) The method of claim 48 further comprising:
receiving a plurality of sets of additional data representing a plurality of additional images of features of a plurality of additional wafer carriers;
calculating a plurality of additional values from the plurality of additional sets of data, the plurality of additional values corresponding to the plurality of features of the additional wafer carriers;
storing the plurality of additional values in the computer readable medium; and
calculating a final value as a function of the first value, the second value and the plurality of additional values.

51. (Original) The method of claim 50 wherein the final value corresponds to one of a mean value, an average value and a median value.

52. (Original) The method of claim 50 further comprising:
receiving a follow-up set of data representing a follow-up image of the feature of a follow-up wafer carrier;

calculating a follow-up value from the follow-up set of data, the follow-up value
corresponding to the follow-up wafer carrier feature; and
comparing the follow-up value with the final value.

53. (Original) The method of claim 50 further comprising:
providing the final value for use by one of a wafer handling tool and a wafer carrier
handling tool.

54. (Previously presented) A method of measuring a mounting structure comprising:
receiving data corresponding to an image representing a plurality of calibration marks on
the mounting structure;
determining a first geometric shape formed by the calibration marks; and
comparing the first geometric shape with a second geometric shape.

55. (Previously presented) A system for analyzing a wafer carrier, comprising:
a processing unit capable of executing software routines;
a frame adapted to be placed adjacent said carrier and having at least two pitch
calibration marks spaced by a predetermined distance; and
program logic executed by the processing unit and adapted to:
receive data representing an image comprising:
a first image portion representing a first location point on the wafer carrier;
and
a second image portion representing a second location point;
receive a set of data representing an image of the span between said two pitch
calibration marks;
calculate a pixel pitch based on said predetermined distance and the number of
pixels of said image of said span between said pitch calibration marks;
and

calculate a value from the first image and based on the calculated pixel pitch, the value representing the distance between the first location point and the second location point.

56. (Original) The system of claim 55 wherein the first location point is a base of a front opening of the wafer carrier and the second location point is a location other than on the wafer carrier.

57. (Original) The system of claim 55 wherein the first location point is a center line of a first slot end wall and the second location point is the center line of a second slot end wall.

58. (Original) The system of claim 55 wherein the first location point is an end wall of one slot tooth measured at one side of an opening of the wafer carrier and the second location point is an end wall of a corresponding opposed slot tooth measured at the other side of the wafer carrier opening, and wherein the value is a slot root.

59. (Original) The system of claim 55 wherein the first location point is a first point on a slot tooth and the second location point is a second point on the slot tooth, and wherein the wafer carrier feature is a profile of the slot tooth.

60. (Original) The system of claim 55 wherein the first location point is a first point on a slot tooth and the second location point is a second point on the slot tooth, and wherein the wafer carrier feature is a slant angle of the slot tooth.

61. (Original) The system of claim 55 wherein the first location point is a base of a front opening of the wafer carrier and the second location point is a centerline of a slot tooth end wall.

62. (Previously presented) A system for analyzing a wafer carrier, comprising:
a frame adapted to be placed adjacent said carrier and having at least two pitch
calibration marks spaced by a predetermined distance;
a processing unit capable of executing software routines; and
program logic executed by the processing unit, comprising:

means for receiving data representing an image of a feature of the wafer carrier,
and a set of data representing an image of the span between said two
pitch calibration marks;

means for calculating a pixel pitch based on said predetermined distance and the
number of pixels of said image of said span between said pitch calibration
marks, and a first value from the image based on the calculated pixel
pitch, the first value corresponding to the wafer carrier feature;

means for retrieving a second value, the second value being derived from other
than the image; and

means for comparing the first value with the second value.

63. (Currently amended) A system for analyzing a wafer carrier, comprising:
a processing unit capable of executing software routines; and
program logic ~~adapted for use with a flatbed scanner and~~ executed by the processing
unit, comprising:

means for receiving ~~from the flatbed scanner~~ a first set of data representing a first
image of a feature of a first wafer carrier;

means for calculating a first value from the first set of data, the first value
corresponding to the first wafer carrier feature; ~~and~~

means for storing the first value in a computer readable medium;

means for retrieving the first value from the computer readable medium; and

means for providing the first value for use by one of a wafer handling tool and a
wafer carrier handling tool.

64. (Original) The system of claim 63 further comprising:
means for receiving additional data corresponding to an identification number for
the first wafer carrier;
means for storing the additional data in the computer readable medium; and
means for associating the additional data with the first value.
65. (Original) The system of claim 64 wherein the additional data is derived from a
bar code.
66. (Cancelled)
67. (Original) The system of claim 63 further comprising:
means for receiving a second set of data representing a second image of the
feature of a second wafer carrier;
means for calculating a second value from the second set of data, the second
value corresponding to the feature of the second wafer carrier; and
means for storing the second value in the computer readable medium.
68. (Currently amended) The system of claim 67 further comprising:
means for retrieving the ~~first and second~~ value ~~values~~ from the computer
readable medium; and
means for performing statistical analysis using the first and second values.
69. (Original) The system of claim 67 further comprising:
means for receiving a plurality of sets of additional data representing a plurality of
additional images of features of a plurality of additional wafer carriers;
means for calculating a plurality of additional values from the plurality of additional
sets of data, the plurality of additional values corresponding to the plurality
of features of the additional wafer carriers;

means for storing the plurality of additional values in the computer readable medium; and

means for calculating a final value as a function of the first value, the second value and the plurality of additional values.

70. (Original) The system of claim 69 wherein the final value corresponds to one of a mean value, an average value and a median value.

71. (Original) The system of claim 69 further comprising:

means for receiving a follow-up set of data representing a follow-up image of the feature of a follow-up wafer carrier;

means for calculating a follow-up value from the follow-up set of data, the follow-up value corresponding to the follow-up wafer carrier feature; and

means for comparing the follow-up value with the final value.

72. (Original) The system of claim 69 further comprising:

means for providing the final value for use by one of a wafer handling tool and a wafer carrier handling tool.

73. (Previously presented) A system for measuring a mounting structure, comprising: a processing unit capable of executing software routines; and program logic executed by the processing unit, and adapted to:

receive data corresponding to an image representing a plurality of calibration marks on the mounting structure;

determine a first geometric shape formed by the calibration marks; and

compare the first geometric shape with a second geometric shape.

74. (Currently amended) An article of manufacture for use in analyzing a wafer carrier, the article of manufacture comprising a computer usable media including at least one computer program embedded therein that causes the computer to perform:

receiving from a flatbed scanner data representing an image comprising:
a first image portion representing a first location point on the wafer carrier; and
a second image portion representing a second location point; and
calculating a value from the image, the value representing the distance between the first
location point and the second location point.

75. (Original) The article of manufacture of claim 74 wherein the first location point is a base of a front opening of the wafer carrier and the second location point is a location other than on the wafer carrier.

76. (Original) The article of manufacture of claim 74 wherein the first location point is a center line of a first slot end wall and the second location point is the center line of a second slot end wall.

77. (Original) The article of manufacture of claim 74 wherein the first location point is an end wall of one slot tooth measured at one side of an opening of the wafer carrier and the second location point is an end wall of a corresponding opposed slot tooth measured at the other side of the wafer carrier opening, and wherein the value is a slot root.

78. (Original) The article of manufacture of claim 74 wherein the first location point is a first point on a slot tooth and the second location point is a second point on the slot tooth, and wherein the wafer carrier feature is a profile of the slot tooth.

79. (Original) The article of manufacture of claim 74 wherein the first location point is a first point on a slot tooth and the second location point is a second point on the slot tooth, and wherein the wafer carrier feature is a slant angle of the slot tooth.

80. (Original) The article of manufacture of claim 74 wherein the first location point is a base of a front opening of the wafer carrier and the second location point is a centerline of a slot tooth end wall.

81. (Cancelled)

82. (Currently amended) An article of manufacture for use in analyzing at least one wafer carrier, the article of manufacture comprising a computer usable media including at least one computer program embedded therein that causes the computer to perform:

receiving ~~from a flatbed scanner~~ a first set of data representing a first image of a feature of a first wafer carrier;

calculating a first value from the first set of data, the first value corresponding to the first wafer carrier feature; and

storing the first value in a computer readable medium;

retrieving the first value from the computer readable medium; and

providing the first value for use by one of a wafer handling tool and a wafer carrier handling tool.

83. (Original) The article of manufacture of claim 82 further comprising:
receiving additional data corresponding to an identification number for the first wafer carrier;

storing the additional data in the computer readable medium; and

associating the additional data with the first value.

84. (Original) The article of manufacture of claim 83 wherein the additional data is derived from a bar code.

85. (Cancelled)

86. (Original) The article of manufacture of claim 82 further comprising:
receiving a second set of data representing a second image of the feature of a second
wafer carrier;
calculating a second value from the second set of data, the second value corresponding
to the feature of the second wafer carrier; and
storing the second value in the computer readable medium.

87. (Currently amended) The article of manufacture of claim 86 further comprising:
retrieving the ~~first and second~~ value values from the computer readable medium; and
performing statistical analysis using the first and second values.

88. (Original) The article of manufacture of claim 86 further comprising:
receiving a plurality of sets of additional data representing a plurality of additional images
of features of a plurality of additional wafer carriers;
calculating a plurality of additional values from the plurality of additional sets of data, the
plurality of additional values corresponding to the plurality of features of the
additional wafer carriers;
storing the plurality of additional values in the computer readable medium; and
calculating a final value as a function of the first value, the second value and the plurality
of additional values.

89. (Original) The article of manufacture of claim 88 wherein the final value
corresponds to one of a mean value, an average value and a median value.

90. (Original) The article of manufacture of claim 88 further comprising:
receiving a follow-up set of data representing a follow-up image of the feature of a follow-
up wafer carrier;
calculating a follow-up value from the follow-up set of data, the follow-up value
corresponding to the follow-up wafer carrier feature; and

comparing the follow-up value with the final value.

91. (Original) The article of manufacture of claim 88 further comprising:
providing the final value for use by one of a wafer handling tool and a wafer carrier
handling tool.

92. (Original) An article of manufacture for use in measuring a mounting structure,
the article of manufacture comprising a computer usable media including at least one computer
program embedded therein that causes the computer to perform:

receiving data corresponding to an image representing a plurality of calibration marks on
the mounting structure;

determining a first geometric shape formed by the calibration marks; and
comparing the first geometric shape with a second geometric shape.